L Number	Hits	Search Text	DB	Time stamp
1	3	4222345.pn.	USPAT;	2003/08/11 08:4
			US-PGPUB;	` .
·			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
2	2	3939798.pn.	USPĀT;	2003/08/11 08:4
		-	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM TDB	
3	5	(("3664295") or ("3636916") or ("3608519") or ("2456708") or ("2391595")).PN.	USPĀT	2003/08/11 08:4
4	11	"3,939,798"	USPAT;	2003/08/11 09:0
•	••	3,557,970	US-PGPUB;	
			EPO; JPO;	
			DERWENT:	
			1	
_	270	(410/710 1 45//245 21 1 - 45//245 22 -1) - 4/(1)	IBM_TDB	2002 /00 /11 00 2
5	270	(118/719.ccls. or 156/345.31.ccls. or 156/345.32.ccls.) and (jet or nozzle)	USPAT;	2003/08/11 09:3
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
6	1	((jet or nozzle) same plasma) and bernouli	USPĀT;	2003/08/11 09:3
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
		. ,	IBM TDB	
7	3	((jet or nozzle) and plasma) and bernouli	USPĀT:	2003/08/11 09:
<b>'</b>		((ct of nozzac) and plasma) and bernoun	US-PGPUB;	2003/ 00/ 11 0/
			EPO; JPO;	
			DERWENT;	
_	_		IBM TDB	2002 (00 (44 05
8 .	5	plasma and bernouli	USPAT;	2003/08/11 09:
			US-PGPUB;	.9
			EPO; JPO;	14
			DERWENT;	, ,
			IBM_TDB	
9	3375	plasma and vortex	USPAT;	2003/08/11 €7:
			US-PGPUB;	
	-	- · · · · · · · · · · · · · · · · · · ·	EPO; JPO;	:
			DERWENT;	
			IBM TDB	
10	262	(plasma and vortex) and ((stage or support or platen or table or susceptor or	USPĀT;	2003/08/11 09:
		chuck or holder or mandrel) with (wafer or substrate))	US-PGPUB;	
		made of mater of mater of outstandy	EPO; JPO;	
			DERWENT;	
			IBM TDB	
11	9	(alsome and example) and ((assess on support on places on schola on support on		2003/08/11 09:
.1	9	(stage or support or platen or table or susceptor or chuck or holder or mandrel) with article) not (plasma and vortex) and (stage or	USPAT;	2005/06/11 09:
			US-PGPUB;	
		support or platen or table or susceptor or chuck or holder or mandrel) with	EPO; JPO;	
		(wafer or substrate)))	DERWENT;	
			IBM_TDB	
12	3	(("6203661") or ("6095582") or ("6040548")).PN.	USPĀT	2003/08/11 09:
13	23	(plasma or vortex) and bernouli	USPAT;	2003/08/11 09:
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM TDB	
L4	23	(plasma or vortex) and bernouli not ((plasma and vortex) and ((stage or support	USPĀT;	2003/08/11 09:
		or platen or table or susceptor or chuck or holder or mandrel) with (wafer or	US-PGPUB;	
		substrate)))	EPO; JPO;	
		outouau)))	DERWENT;	
			IBM_TDB	2002/20/11 15
15	4331	((vortex or bernouli) same (stage or support or platen or table or susceptor or	USPAT;	2003/08/11 10:
		chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or	US-PGPUB;	
		platen or table or susceptor or chuck or holder or mandrel) with (wafer or	EPO; JPO;	
		substrate)))	DERWENT;	
		l	IBM TDB	I

Search History 8/11/03 1:28:19 PM Page 1 C:\APPS\EAST\Workspaces\08860763.wsp

16	575	(((vortex or bernouli) same (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or	USPAT; US-PGPUB;	2003/08/11 10:03
		platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and (plasma or ioniz\$5)	EPO; JPO; DERWENT; IBM TDB	
17	133	zervigon.xa.	USPĀT; US-PGPUB; EPO; JPO;	2003/08/11 10:13
			DERWENT; _IBM_TDB	
18	421	((((vortex or bernouli) same (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and (plasma or ioniz\$5)) and (wafer or substrate or article or work or semiconductor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/08/11 10:40
19	1802	((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/08/11 10:40
20	1761	(((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) not (((((vortex or bernouli) same (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and (plasma or ioniz\$5)) and (wafer or substrate or article or work or semiconductor))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/11 10:40
21	487	((((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) not (((((vortex or bernouli) same (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and (plasma or ioniz\$5)) and (wafer or substrate or article or work or	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/11 11:49
22	5	semiconductor) 279/\$.ccls. and (bernouli or vortex)	USPAT; US-PGPUB; EPO; JPO; DERWENT;	2003/08/11 11:52
23	0	"bernouli chuck"	IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/11 11:56
24	1166	(((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and @ay<1996	USPĀT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/08/11 11:58
25	860	((((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and @ay<1996) not (((((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) not ((((vortex or bernouli) same (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and (plasma or ioniz\$5)) and (wafer or substrate or article or work or semiconductor))) and (wafer or substrate or article or work or semiconductor))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/11 11:58

(heraruli or vortex) as wood

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26	271	(((((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or	USPAT; US-PGPUB; EPO; JPO;	2003/08/11 11:5
		substrate)))) and @ay<1996) not (((((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder	DERWENT; IBM_TDB	
		or mandrel) with (wafer or substrate)))) not (((((vortex or bernouli) same (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or		
		chuck or holder or mandrel) with (wafer or substrate)))) and (plasma or ioniz\$5))— and (wafer or substrate or article or work or semiconductor))) and (wafer or substrate or article or work or semiconductor))) and (jet or nozzle)		
27	39	(((((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and @ay<1996) not (((((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) not ((((vortex or bernouli) same (stage or	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/11 12:0
		support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and (plasma or ioniz\$5)) and (wafer or substrate or article or work or semiconductor))) and (wafer or substrate or article or work or semiconductor))) and plasma	A POD A TI	2002/00/44 42
28	252	((((((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and @ay<1996) not (((((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) not ((((vortex or bernouli) same (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/11 12:0
	- 40	chuck or holder or mandrel) with (wafer or substrate)))) and (plasma or ioniz\$5)) and (wafer or substrate or article or work or semiconductor))) and (wafer or substrate or article or work or semiconductor))) and (jet or nozzle)) not ((((((vortex or bernouli) with (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and @ay<1996) not ((((((vortex or bernouli) with (stage or support or platen or table or suspend or substrate)))) and (((((vortex or bernouli) with (stage or support or platen or table or suspend of (vortex or bernouli))))		•
		platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) not ((((vortex or bernouli) same (stage or support or platen or table or susceptor or chuck or holder or mandrel)) not ((plasma and vortex) and ((stage or support or platen or table or susceptor or chuck or holder or mandrel) with (wafer or substrate)))) and (plasma or ioniz\$5)) and (wafer or substrate or article or work or semiconductor))) and (wafer or substrate or article or work or semiconductor))) and plasma)		
-	8424	l a a a a a a a a a a a a a a a a a a a	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/08/11 08:3
-	7990	137/262-264.ccls. or 137/454.2 or 137/560.ccls. or 137/561r.ccls. or 137/561a.ccls. or 137/571-576.ccls. or 137/590.ccls. or 137/594-596.ccls. or 137/599.01.ccls. or 137/599.05-599.07.ccls. or 137/602.ccls.	USPĀT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/08/10 16:3
-	2239	141/285-286.ccls. or 141/37.ccls. or 141/44-47.ccls. or 141/54.ccls. or 141/301-302.ccls. or 141/367.ccls.	USPĀT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/08/10 16:3
•	453	261/127.ccls. or 261/131.ccls. or 261/146-147.ccls. or 261/150.ccls.	USPĀT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/08/10 16:3

	2567	261/19-22.ccls. or 261/23.1.ccls. or 261/40.ccls. or 261/42.ccls. or	USPAT;	2003/08/10 16:35
	2507	261/62-63.ccls.	US-PGPUB;	2003/ 00/ 10 10:55
			EPO; JPO;	
			DERWENT;	
	(003	261/64.1.ccls. or 261/65.ccls. or 261/75-76.ccls. or 261/94-96.ccls. or	IBM_TDB USPAT:	2003/08/10 16:35
-	6993	261/64.1.ccis. or 261/65.ccis. or 261/75-76.ccis. or 261/94-76.ccis. or 261/108-109.ccis. or 261/113.ccis. or	US-PGPUB:	2003/06/10 10:55
		261/114.1.ccls.	EPO; IPO;	
		2017 11 (1.00)	DERWENT;	
			_IBM_TDB	
-	28016	(118/715.ccls. or 118/728.ccls. or 118/50.ccls. or 156/345.29.ccls. or	USPĀT;	2003/08/10 16:35
		156/345.33.ccls. or 156/345.34.ccls. or 156/345.35.ccls. or 156/345.36.ccls. or	US-PGPUB;	
		156/345.26.ccls. or 156/345.51.ccls.) or (137/262-264.ccls. or 137/454.2 or	EPO; JPO;	
		137/560.ccls. or 137/561r.ccls. or 137/561a.ccls. or 137/571-576.ccls. or	DERWENT;	
		137/590.ccls. or 137/594-596.ccls. or 137/599.01.ccls. or 137/599.05-599.07.ccls. or 137/602.ccls.) or (141/285-286.ccls. or 141/37.ccls. or 141/44-47.ccls. or	IBM_TDB	
		141/54.ccls. or 141/301-302.ccls. or 141/367.ccls.) or (261/127.ccls. or		
		261/131.ccls. or 261/146-147.ccls. or 261/150.ccls.) or (261/19-22.ccls. or		
		261/23.1.ccls. or 261/40.ccls. or 261/42.ccls. or 261/62-63.ccls.) or		
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		261/100-102.ccls. or 261/105.ccls. or 261/108-109.ccls. or 261/113.ccls. or		
		261/114.1.ccls.)		( (
-	8	((118/715.ccls. or 118/728.ccls. or 118/50.ccls. or 156/345.29.ccls. or	USPAT;	2003/08/10 16:36
		156/345.33.ccls. or 156/345.34.ccls. or 156/345.35.ccls. or 156/345.36.ccls. or	US-PGPUB;	
		156/345.26.ccls. or 156/345.51.ccls.) or (137/262-264.ccls. or 137/454.2 or 137/560.ccls, or 137/561r.ccls. or 137/561a.ccls. or 137/571-576.ccls. or	EPO; JPO; DERWENT;	
		137/590.ccls. or 137/594-596.ccls. or 137/599.01.ccls. or 137/599.05-599.07.ccls.	IBM TDB	
		or 137/602.ccls.) or (141/285-286.ccls. or 141/37.ccls. or 141/44-47.ccls. or	IDIN_IDD	
		141/54.ccls. or 141/301-302.ccls. or 141/367.ccls.) or (261/127.ccls. or		
		261/131.ccls. or 261/146-147.ccls. or 261/150.ccls.) or (261/19-22.ccls. or	1	
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		261/100-102.ccls. or 261/105.ccls. or 261/108-109.ccls. or 261/113.ccls. or		
		261/114.1.ccls.)) and planetary and (boat or carrier) and (plasma or ion)	<u> </u>	•